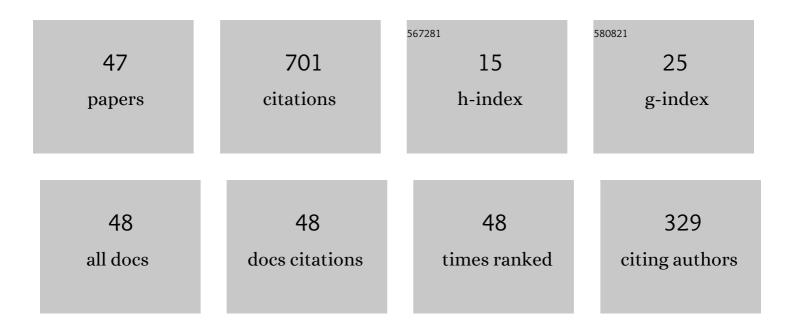


## List of Publications by Year in descending order

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VACUOLI

#	Article	IF	CITATIONS
1	Morphology and distribution of subsurface damage in optical fused silica parts: Bound-abrasive grinding. Applied Surface Science, 2011, 257, 2066-2073.	6.1	81
2	Vibration-assisted dry polishing of fused silica using a fixed-abrasive polisher. International Journal of Machine Tools and Manufacture, 2014, 77, 93-102.	13.4	67
3	The characteristics of optics polished with a polyurethane pad. Optics Express, 2008, 16, 10285.	3.4	43
4	A method for evaluating subsurface damage in optical glass. Optics Express, 2010, 18, 17180.	3.4	43
5	Laser-induced damage characteristics in fused silica surface due to mechanical and chemical defects during manufacturing processes. Optics and Laser Technology, 2017, 91, 149-158.	4.6	39
6	Laser induced damage characteristics of fused silica optics treated by wet chemical processes. Applied Surface Science, 2015, 357, 498-505.	6.1	31
7	Tentative investigation towards precision polishing of optical components with ultrasonically vibrating bound-abrasive pellets. Optics Express, 2012, 20, 568.	3.4	28
8	Post-processing of fused silica and its effects on damage resistance to nanosecond pulsed UV lasers. Applied Optics, 2016, 55, 3017.	2.1	27
9	Proposal of a tilted helical milling technique for high-quality hole drilling of CFRP: analysis of hole surface finish. International Journal of Advanced Manufacturing Technology, 2019, 101, 1041-1049.	3.0	24
10	Generation of Scratches and Their Effects on Laser Damage Performance of Silica Glass. Scientific Reports, 2016, 6, 34818.	3.3	23
11	Function of liquid and tool wear in ultrasonic bound-abrasive polishing of fused silica with different polishing tools. Optik, 2014, 125, 4064-4068.	2.9	22
12	1.6 Precision Grinding, Lapping, Polishing, and Post-Processing of Optical Glass. , 2017, , 154-170.		22
13	Resistance of Scratched Fused Silica Surface to UV Laser Induced Damage. Scientific Reports, 2019, 9, 10741.	3.3	22
14	Phase explosion induced by high-repetition rate pulsed laser. Applied Surface Science, 2010, 256, 6649-6654.	6.1	19
15	Chemo-mechanical manufacturing of fused silica by combining ultrasonic vibration with fixed-abrasive pellets. International Journal of Precision Engineering and Manufacturing, 2012, 13, 2163-2172.	2.2	17
16	Top-hat and Gaussian laser beam smoothing of ground fused silica surface. Optics and Laser Technology, 2020, 127, 106141.	4.6	16
17	Laser plasma-induced damage characteristics of Ta <sub>2</sub> O <sub>5</sub> films. Optical Materials Express, 2019, 9, 3132.	3.0	16
18	Producing fused silica optics with high UV-damage resistance to nanosecond pulsed lasers. Proceedings of SPIE, 2015, , .	0.8	13

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#	Article	IF	CITATIONS
19	Ultrasonicâ€assisted wet chemical etching of fused silica for highâ€power laser systems. International Journal of Applied Glass Science, 2018, 9, 288-295.	2.0	13
20	Surface characteristics of an optical component manufactured with a polyurethane lap. Applied Optics, 2009, 48, 737.	2.1	12
21	Study of morphological feature and mechanism of potassium dihydrogen phosphate surface damage under a 351  nm nanosecond laser. Applied Optics, 2018, 57, 10334.	1.8	10
22	Laser induced damage due to scratches in the surface of nonlinear optical crystals KH2PO4 (KDP). Journal of the European Optical Society-Rapid Publications, 2017, 13, .	1.9	9
23	Effect of scratches on the damage characteristics of fused silica optics under extremely-high impact load. International Journal of Mechanical Sciences, 2022, 219, 107099.	6.7	9
24	The ablation of Ta2O5 film by pulsed nanosecond Gaussian laser beams. Optik, 2015, 126, 2327-2330.	2.9	8
25	Improving UV laser damage threshold of fused silica optics by wet chemical etching technique. Proceedings of SPIE, 2015, , .	0.8	8
26	Plasma-based isotropic etching polishing of synthetic quartz. Journal of Manufacturing Processes, 2020, 60, 447-456.	5.9	8
27	The early transient dynamics reaction of KDP surface during nanosecond laser breakdown. AIP Advances, 2019, 9, .	1.3	7
28	Effects of Wet Chemical Etching on Scratch Morphology and Laser Damage Resistance of Fused Silica. Silicon, 2020, 12, 425-432.	3.3	7
29	Ultraviolet laser damage properties of single-layer SiO <sub>2</sub> film grown by atomic layer deposition. Optical Materials Express, 2020, 10, 1981.	3.0	7
30	Energy transmissivity of high-power nanosecond laser pulse focused on glass. Optik, 2010, 121, 2213-2216.	2.9	6
31	Formation mechanism of bubbles in the crack healing process of fused silica using a CO <sub>2</sub> laser. Optics Express, 2021, 29, 32089.	3.4	5
32	Effect of laser pulse duration and fluence on DKDP crystal laser conditioning. Applied Optics, 2020, 59, 5240.	1.8	5
33	Broadband terahertz antireflective microstructures on quartz crystal surface by CO <sub>2</sub> laser micro-processing. Optics Express, 2019, 27, 18351.	3.4	5
34	On the mechanism of multi-pulses induced damage in dielectrics. Optik, 2013, 124, 1528-1531.	2.9	4
35	Recent progress in bound-abrasive polishing of fused silica glass. Proceedings of SPIE, 2015, , .	0.8	4
36	Threshold fluences for conditioning, fatigue and damage effects of DKDP crystals. Optical Materials, 2019, 91, 199-204.	3.6	4

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37	The characteristics of Ta2O5 films deposited by radio frequency pure oxygen ion assisted deposition (RFOIAD) technology. Journal of Applied Physics, 2017, 121, .	2.5	3
38	The Surface Layer of Fused Silica Finished by Various Polishing Techniques. , 2010, , .		2
39	Hybrid polishing of fused silica glass with bound-abrasive polishers in conjunction with vibration. , 2012, , .		2
40	Precision manufacturing of fused silica glass by combining bound-abrasive polishing with ultrasonic vibration. Proceedings of SPIE, 2012, , .	0.8	2
41	Image processing identification of laser damage induced by ns-pulsed lasers. Optik, 2013, 124, 1940-1942.	2.9	2
42	Investigation of the formation mechanism of the fluorocarbon film in CF4 plasma processing of fused silica. Optik, 2020, 202, 163693.	2.9	2
43	Elimination of X-rays irradiated defects in fused silica by laser conditioning. Optics Communications, 2021, 483, 126639.	2.1	1
44	Broadband absorption coating for large-curvature surfaces by atomic layer deposition. Applied Optics, 2021, 60, 5759.	1.8	1
45	Study on IR laser smoothing of ground surface on fused silica. , 2019, , .		1
46	Investigation on the influence of the CO2 laser parameters on the defect healing process of fused silica. , 2021, , .		0
47	Modeling and analysis of surface roughness in fused silica by CO2 laser smoothing. , 2021, , .		Ο